

**Form 1449 (Modified)**

**Information Disclosure Statement By Applicant**

(Use Several Sheets if Necessary)

**U.S. Patent Documents**

**Foreign Patent or Published Foreign Patent Application**

**Other Documents**

**Examiner Initial**

**No.**

**Patent No.**

**Date**

**Patentee**

**Class**

**Sub-class**

**Filing Date**

**Atty Docket No.**

**Application No.:**

**Applicant:**

**Filing Date**

**Group**

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**MAY 03 2001**

**TC 1700**

**EP 0702392A**

**WO 00/03064**

**O'Hanlon J F: "Advances In Vacuum Contamination Control For Electronic Materials Processing". Journal Of Vacuum Science And Technology: Part A, US, American Institute Of Physics. New York, vol. 5, no. 4, Part 3, 1 July 1987 (1987-07-01), pages 2067-2072.**

**Examiner**

**Date Considered**

**Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.**

**Pg. 1 of 1**